

Summary

In the recent years, FBK developed “high-density” silicon photomultipliers (HD-SiPMs) → deep trenches, obtaining small cells, high fill-factor (FF) → high photon detection efficiency (PDE).
New development → **Ultra-High Density SiPM (RGB-UHD)**, with very small cell size. → **Cell pitches: 5 μm , 7.5 μm , 10 μm , 12.5 μm , 15 μm .**
Problem: in a very small cell, the “border effect” dramatically reduces the effective FF (much smaller than the nominal FF) → it is important to overcome this issue.
First solution: UHD-NGR: we **modified the doping profiles inside the cell** (i.e. the SPAD), developing the “new guard ring” (NGR) structure. → PDE is significantly improved but much higher DCR.
New solutions: based on new TCAD simulation we developed 2 new technological solution + cell layout optimization → **newest version of UHD-SiPM**, with **high PDE but lower DCR**.

UHD-SiPM technology

Aggressive layout and technological features:

- Non-active region reduced to $\sim 1\mu\text{m}$ (including half of trench width)
- SPAD with circular active area
- Honeycomb configuration of cells

Very high cell density + fast cell recovery

- 5.0 μm cell → ~ 40000 cell/ mm^2
- 12.5 μm cell → ~ 7400 cells/ mm^2
- Very high dynamic range achievable

High FF despite the very small cell pitch

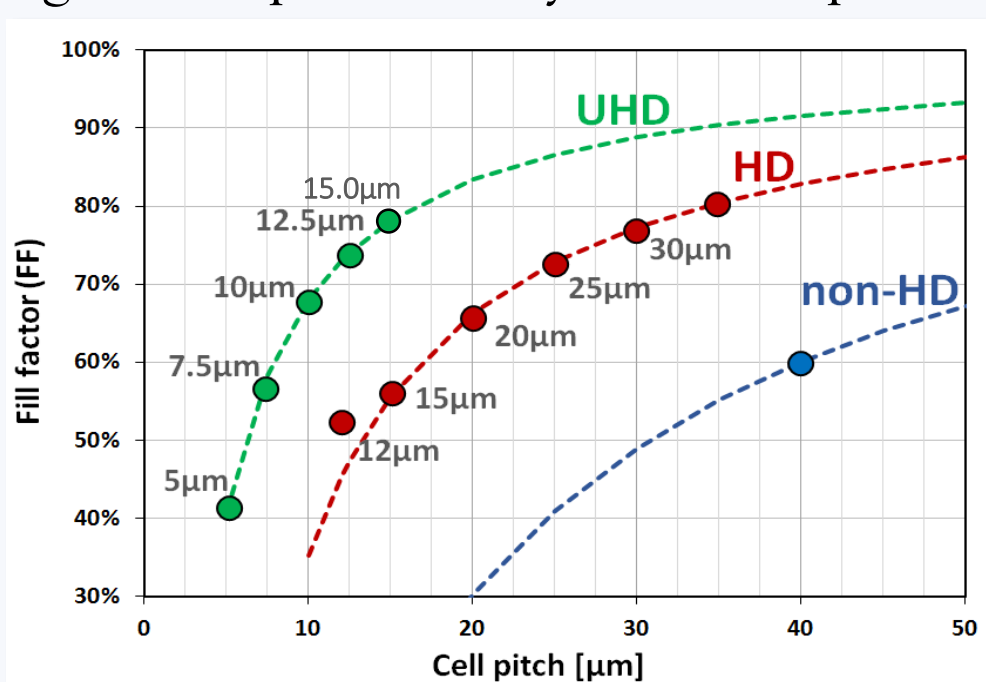


Fig.3: Nominal FF vs. cell pitch, for different technologies

- Applications: calorimetry (high linearity + radiation hardness); gamma imaging in proton therapy (high linearity), high-energy physics experiments (radiation hardness), etc.

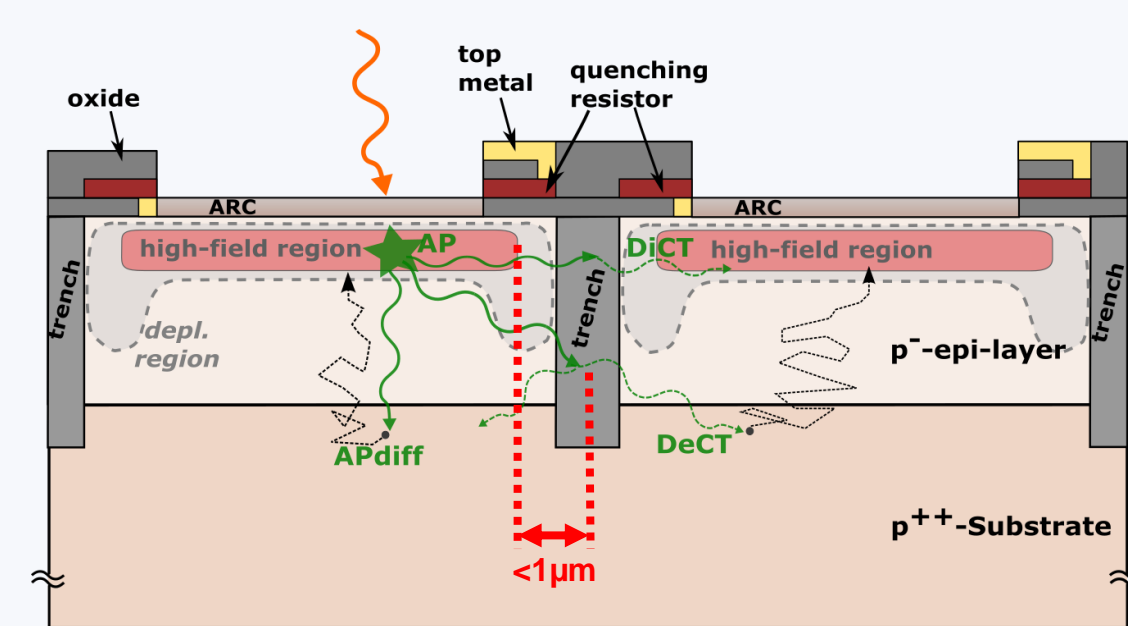


Fig.1: Cross-section of the UHD-SiPM cells, with trench separation

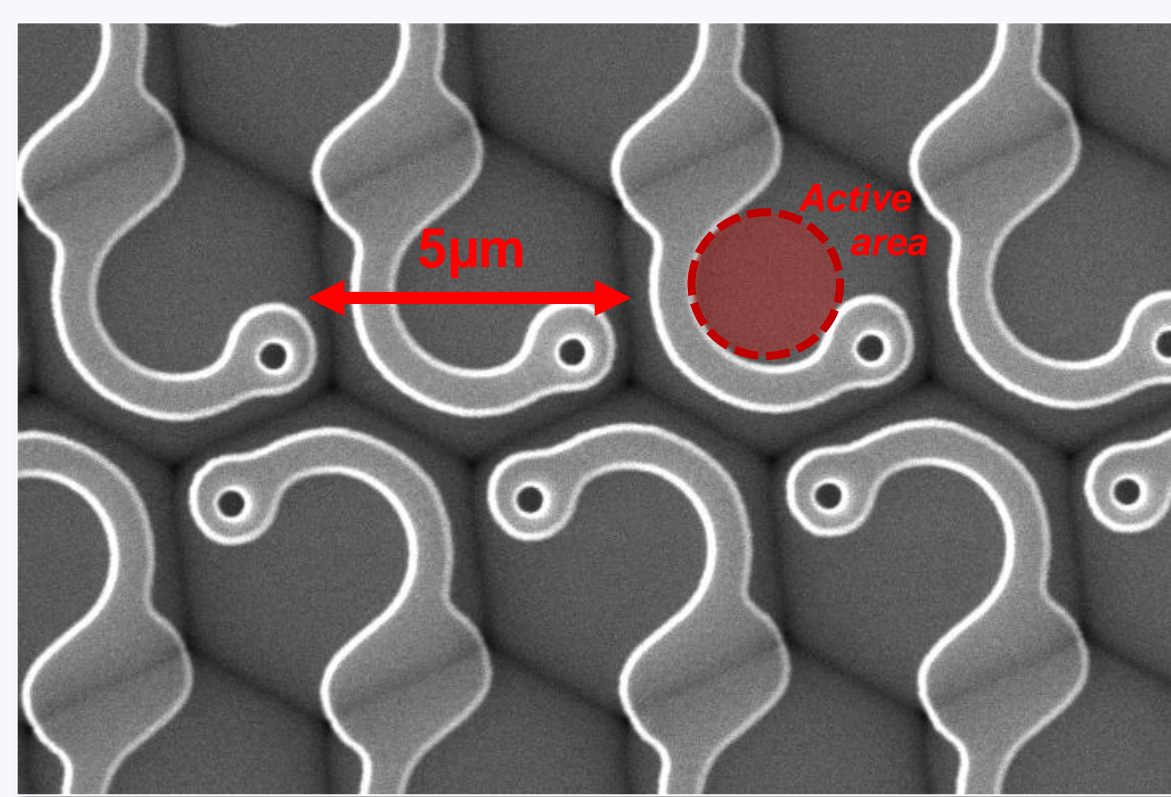


Fig.2: SEM image of 5 μm pitch SiPM, showing hexagonal cells and polysilicon resistors on top

Problem: important dead-border

- UHD SiPMs have very small cell-pitch → very small SPAD size
 - Border region becomes very important.
 - **Effective active area significantly smaller** than design active area, eventually preventing correct working of the 5 μm cell.

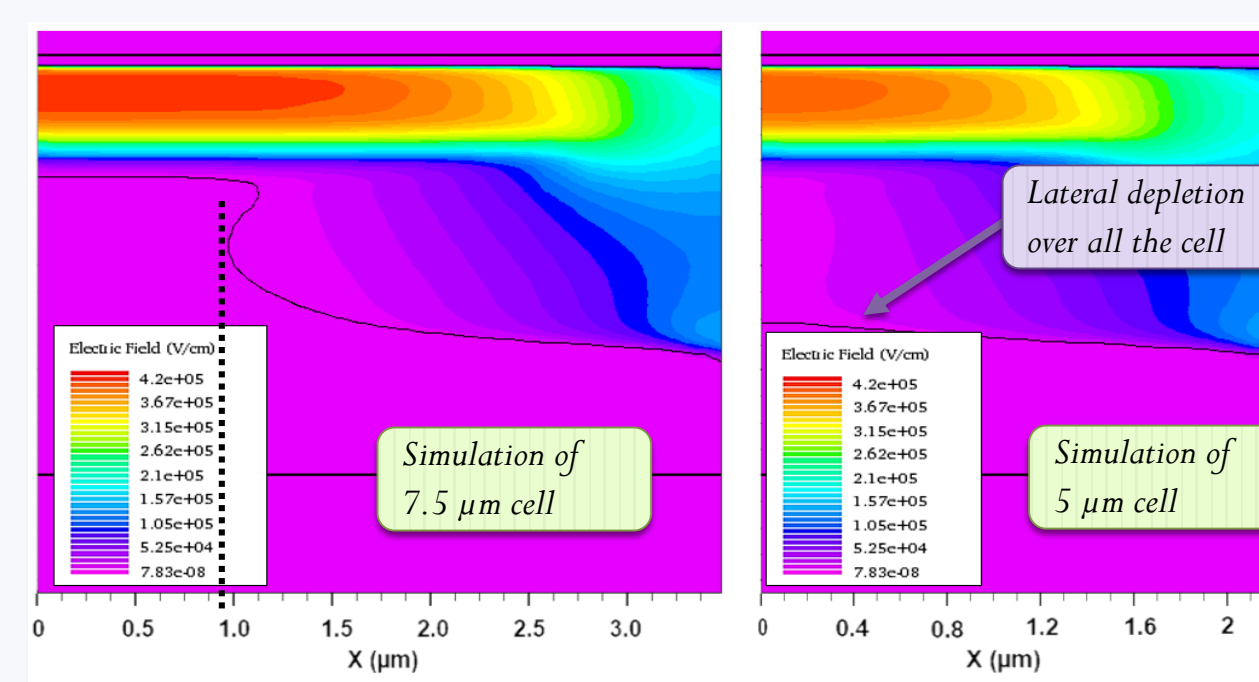


Fig.4: TCAD simulation of electric field in the SPADs (at breakdown voltage): SiPM with 7.5- μm cell pitch (left) and 5 μm cell pitch (right). In 5- μm cell case, the “central active area” is no more present

- 1st optimization with TCAD simulation → “new guard ring” structure has been developed in Q4-2016:
 - PDE significantly improved but primary noise was also significantly higher.
 - This was probably due to high electric field very close to the silicon/trench interface.

- 2nd (new) optimization of the structure and fine tuning of high-field region distance from trenches.

Results:

- **New UHD NGR2 version**
- **UHD low-field (LF) version**

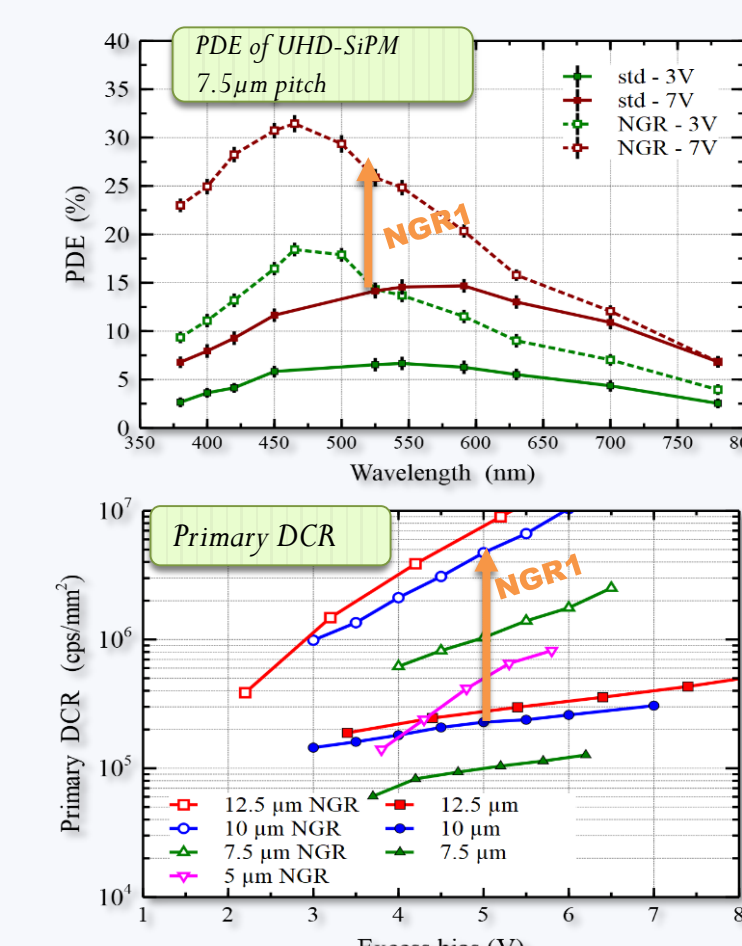


Fig.5: PDE (545nm) and DCR of old “std.” and NGR1 SiPMs

New UHD SiPMs: optimized structures

- Tested and compared different structures, new low-field (LF) and the new “new guard ring 2” (NGR2) UHD-SiPMs → **RESULTS: optimized structures with low dark count rate, good PDE and fast signals.**

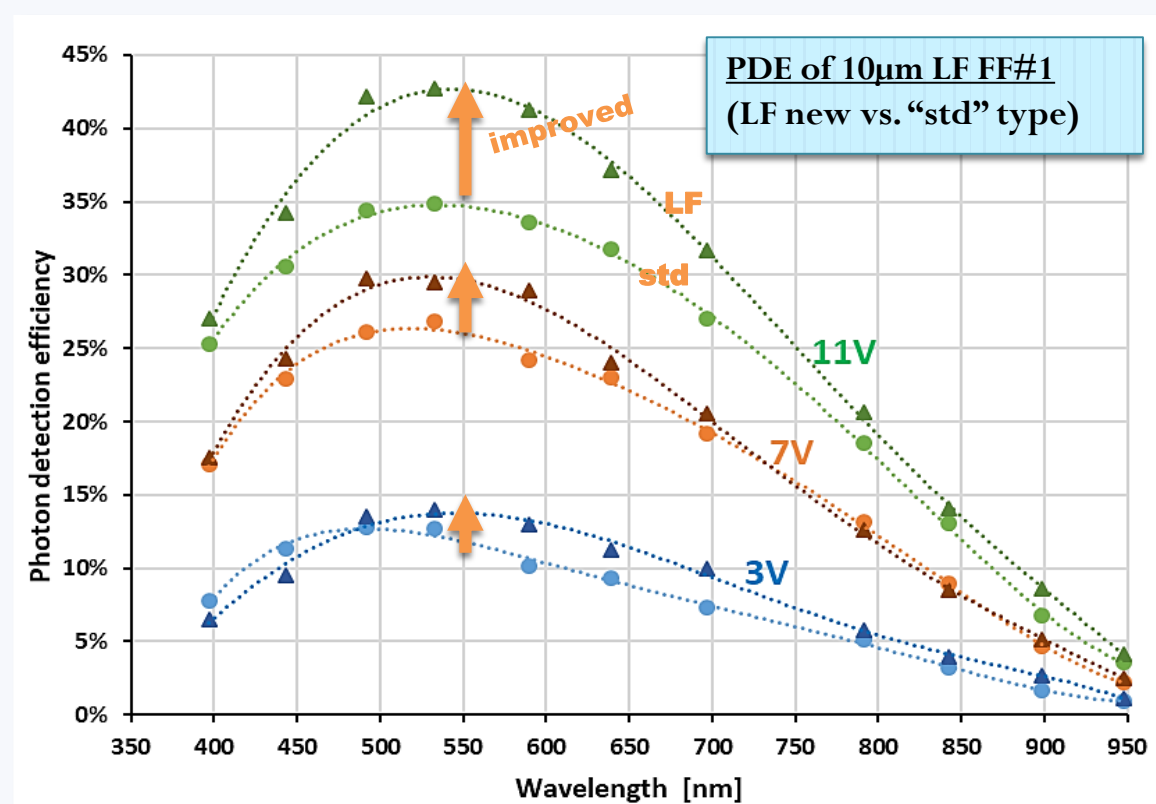


Fig.6: PDE of UHD-SiPM with 10 μm pitch. Comparison between new LF vs. old std. version at 3V, 7V and 11V of excess bias.

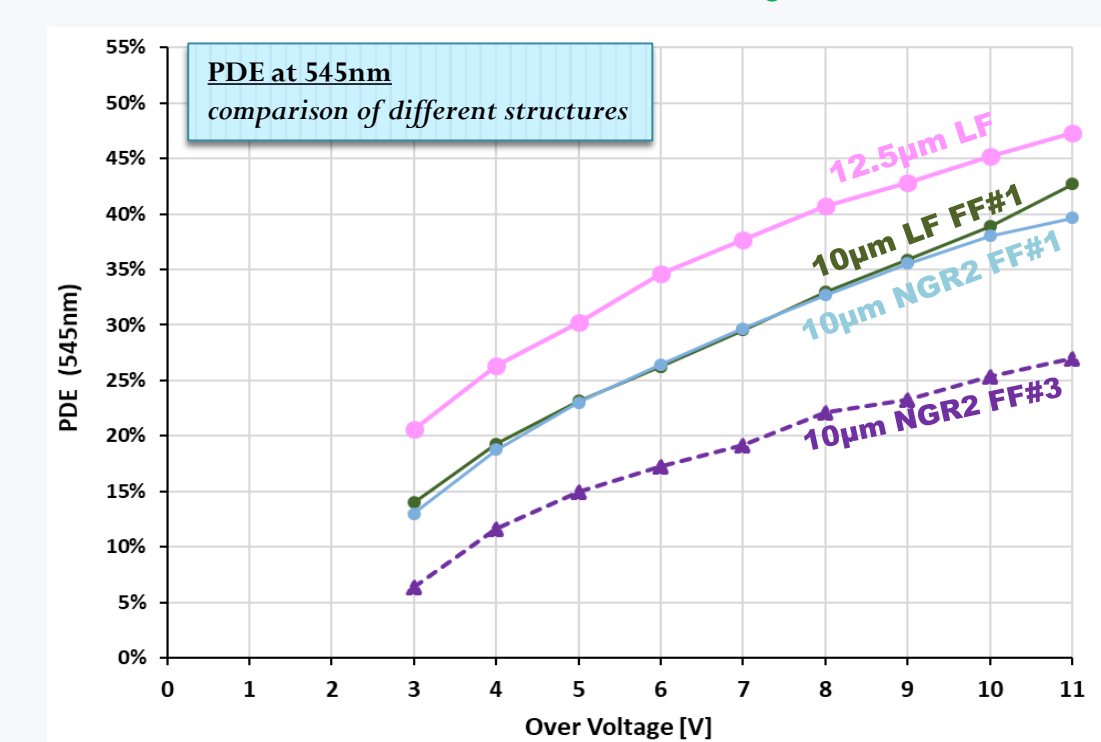


Fig.7: PDE comparison (at 545nm) of different UHD SiPMs: 10 μm FF#1 SiPMs; 12 μm LF SiPM and 10 μm FF#3 SiPM.

Tested SiPMs

- 12.5 μm LF SiPM
- 10 μm SiPM LF & NGR2 SiPMs (tested different layouts → find best tradeoff PDE vs noise)
FF#1=68% FF#2=60% FF#3=54%
- 7.5 μm LF SiPM
- 5 μm NGR2 SiPM

Optimization result: DCR comparable with “std” version, but PDE has been improved

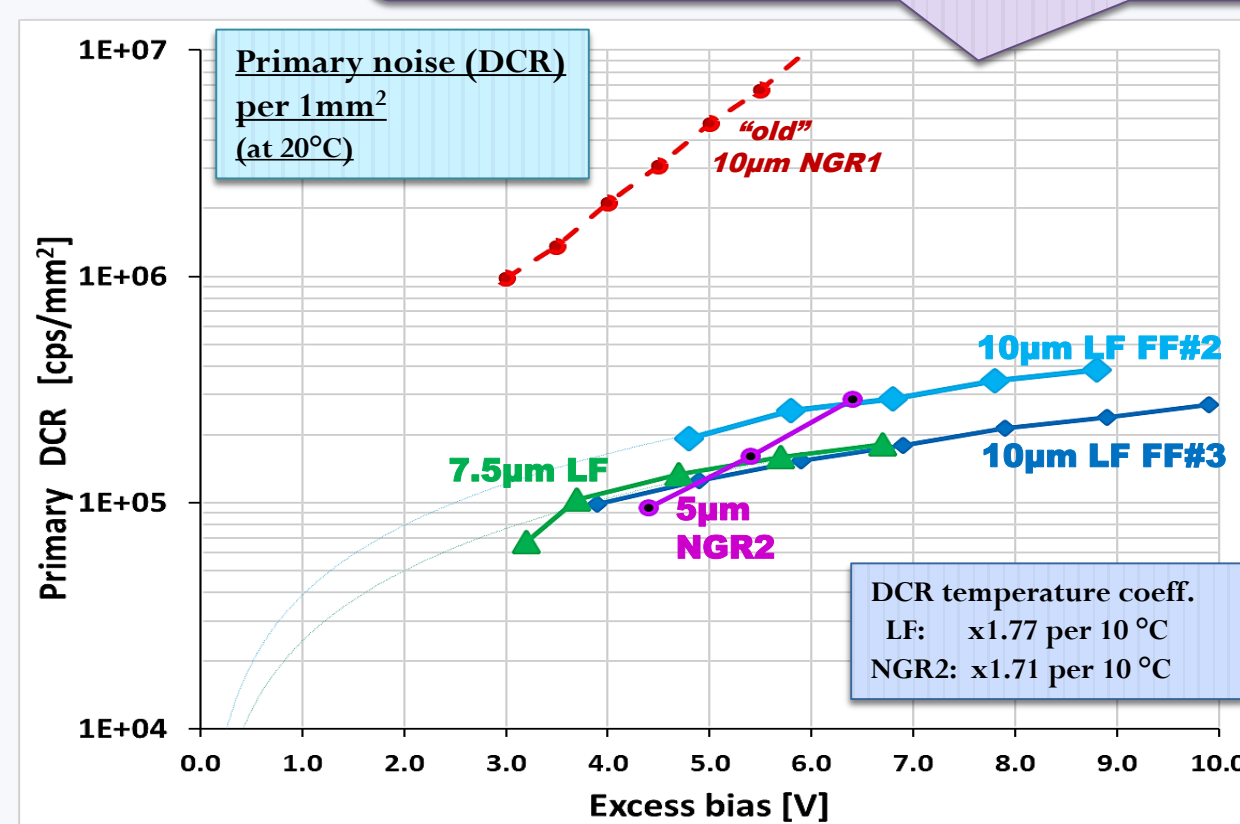


Fig.8: Primary dark count rate of UHD SiPMs (LF and NGR2), compared to “old” NGR1.

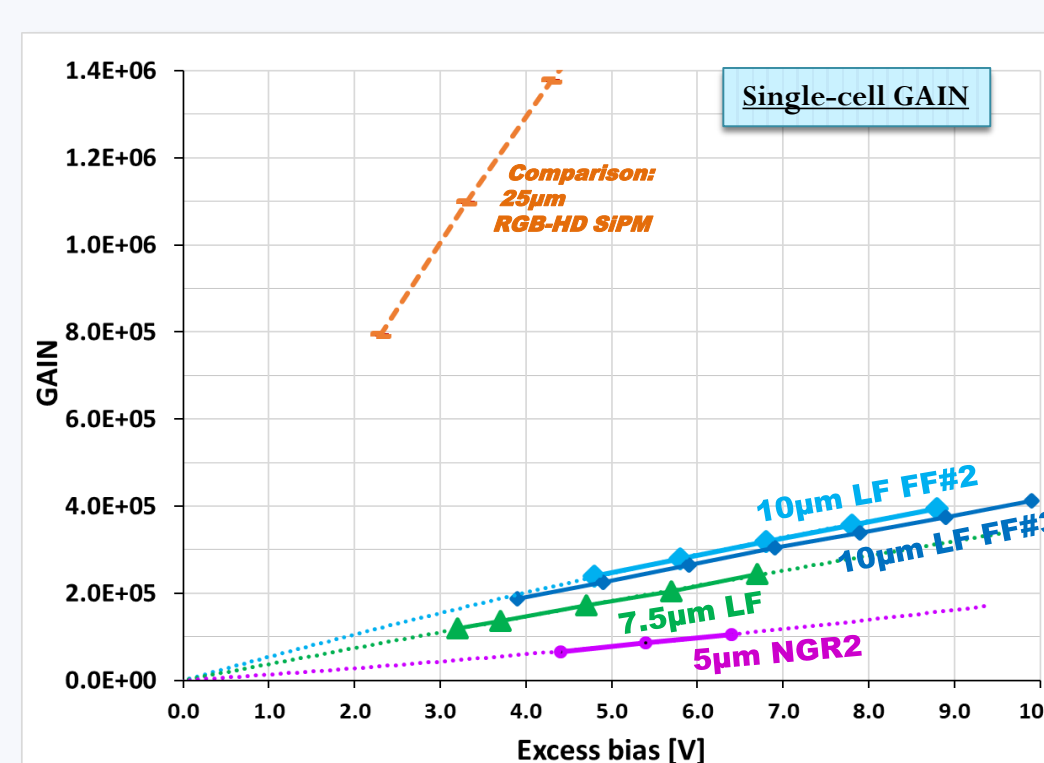


Fig.9: Single-cell gain of UHD SiPMs (compared with FBK high-density 25 μm SiPMs).

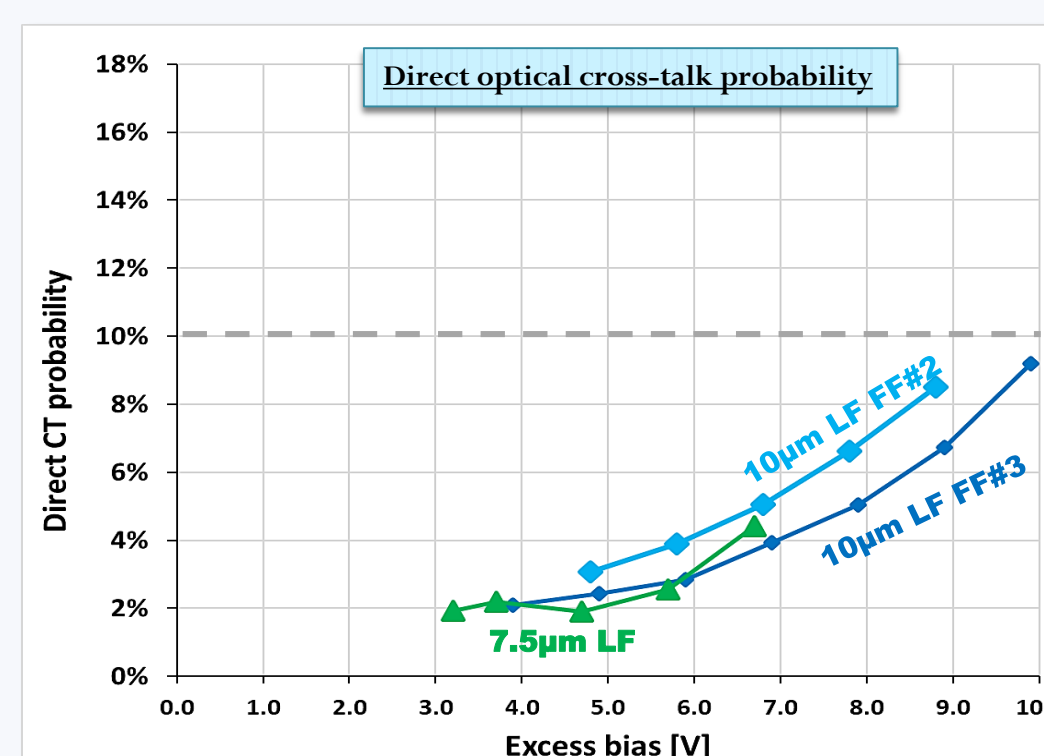


Fig.10: Direct crosstalk probability of UHD SiPMs

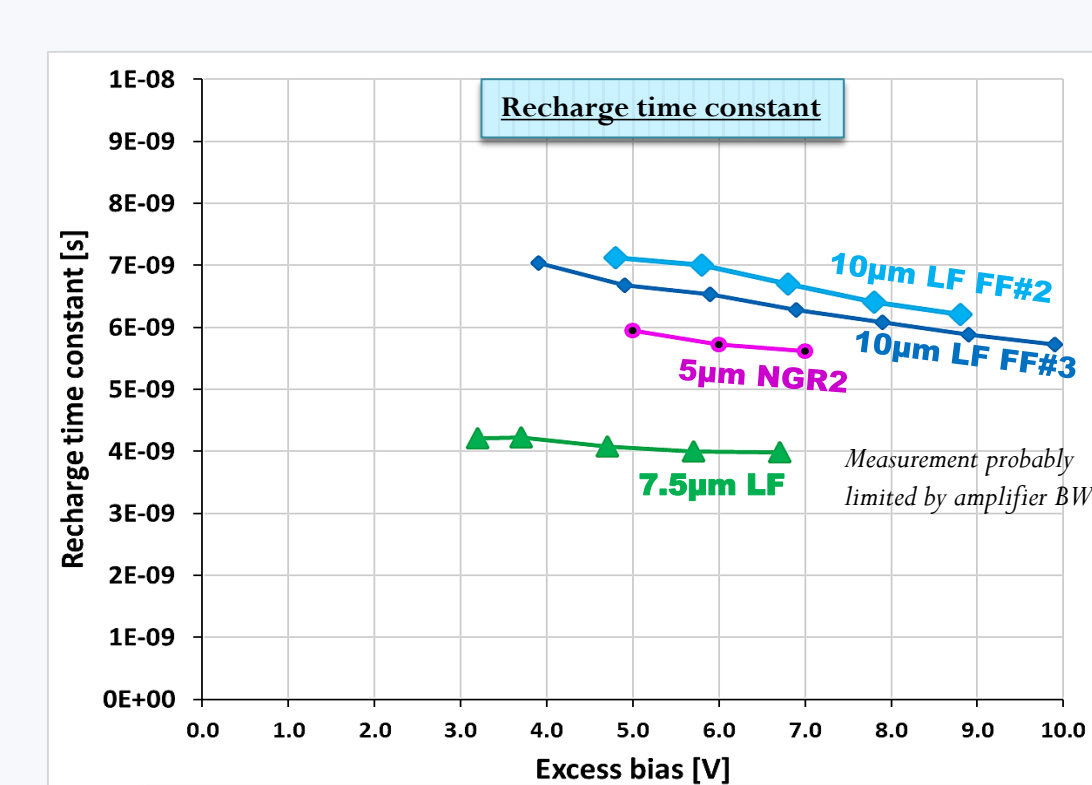


Fig.11: Recharge time constants (top) and screenshot from oscilloscope of single-cell signal of 7.5 μm pitch SiPM (bottom).

Conclusions

- Ultra high density (UHD) SiPM technology has been developed and optimized during last years.
- The goal was to increase the effective FF, thus the detection efficiency, while not increasing the noise (dark count rate).
- As a result of the optimization → new upgraded versions, featuring modified edge structure and lower overall electric fields at the junction.
- Small cells provide increased radiation hardness. R&D is ongoing to reduce electric field in the cell, for further improved resistance to radiation damage.

References

- V. Regazzoni et.al. JINST, 2017, 12, P07001.
- F. acerbi et. al., IEEE j. of Selec. Topic. quant. Elect., v.24, n.2, p. 3800608, 2018.